

P.O. Box 1450

Sir:

Commissioner for Patents

Alexandria, VA 22313-1450

RICHARD E. JENKINS

JEFFREY L. WILSON

ARLĖS A. TAYLOR, JR.

**GREGORY A. HUNT** 

E. ERIC MILLS

BENTLEY J. OLIVE

MICHAEL J. CROWLEY

\*CHRÍS PERKINS, PH.D.

"JAMES DALY IV, PH.D.

JEFFREY CHILDERS, PH.D.

OF COUNSEL SOROJINI BISWAS

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"LICENSED ONLY IN KY

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on April 13, 2004.

Gayle W. Chaney

Date of Signature

U.S. Patent Application Serial No. 10/801,781 for

PROCESS FOR PRODUCING AN ETCHING MASK ON A MICROSTRUCTURE, IN PARTICULAR A SEMICONDUCTOR

STRUCTURE WITH TRENCH CAPACITORS, AND CORRESPONDING USE OF THE ETCHING MASK

Our Ref. No. 1406/189

Please find enclosed in connection with the subject U.S. patent application the following documents:

- 1. Information Disclosure Statement (2 pages);
- 2. Form PTO-1449 (1 page) in duplicate;
- Copy of German Patent Office Action dated 2/11/04; 3.
- Copies of cited references (5 references); and 4.
- A return-receipt postcard to be returned to us with the U.S. Patent and 5. Trademark Office filing stamp thereon.

Although no fee is believed to be due, the Commissioner is hereby authorized to charge any fees associated with the filing of this correspondence to Deposit Account No. 50-0426.

Respectfully submitted,

JENKINS, WILSON & TAYLOR, P.A.

Richard E. Jenkins

Registration No. 28,428

REJ/gwc

**Enclosures** 

Customer No. 25297

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PATENT

Gayle W. Chaney
Date of Signature

Lange W. Chaney
4-13-04

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Moll et al. Group Art Unit: Not Assigned

Serial No.: 10/801,781 Examiner: Not Assigned

Filed: March 16, 2004 Docket No.: 1406/189

Confirmation No.:

For: PROCESS FOR PRODUCING AN ETCHING MASK ON A MICROSTRUCTURE,

IN PARTICULAR A SEMICONDUCTOR STRUCTURE WITH TRENCH

CAPACITORS, AND CORRESPONDING USE OF THE ETCHING MASK

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## INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In accordance with 37 C.F.R. 1.56, 1.97, and 1.98, applicants' undersigned attorney brings to the attention of the Patent and Trademark Office the documents listed on the attached form PTO-1449. Copies of the references as well as Form PTO-1449 are attached hereto. This is not to be construed as a representation that a search has been made or that a reference is relevant merely because cited.

Applicant hereby certifies that each item of information contained in this statement was cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.

Appln. No.: 10/801,781

Early passage of the subject application to issue is earnestly solicited.

Although it is believed that no fee is due, the Commissioner is hereby authorized to charge any fees associated with the filing of this Information Disclosure Statement to Deposit Account No. <u>50-0426</u>.

Respectfully submitted,

JENKINS, WILSON & TAYLOR, P.A.

10. 4-13-DT

Richard E. Jenkins

Registration No. 28,428

REJ/gwc

**Enclosures** 

Customer No. 25297

1406/189

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FORM 1449 U.S. Department of Commerce				Attorney Docket No. 1406/189			Serial No.	
Patent and Trademark Office							10/801,781	
List of Documents Cited by Applicant								
•				Applicant(s): Moll et al.				
•				Filing Date: March 16, 2004			Group	
		U.S. PATI	ENT DO	CUMENTS				
Examiner Initial	Document Number	Date	Name		Class	Subclass	Filing date if Appropriate	
	5,378,316	01/03/1995	Franke et al.					
		FOREIGN PA	ATENT	DOCUMEN	TS			
	Document Number	Date	Country		Name of Patentee or Applicant		Translation Yes   No	
	EP 0932187 A2	07/28/1999	EP		IBM		Yes	
	DE 198 44 102 C2	04/06/2000	Ge	ermany	Siemens AG		No	
	DE 100 00 003 C2	07/12/2001	Ge	ermany	ny Infineon Technologies AG		No	
	DE 199 58 904 C2	06/21/2001	Ge	ermany	Infineon Technologies AG		No	
	OTHER DOCUMEN	NTS (Including	g Author	, Title, Date	, Pertinen	t Pages, Etc	.)	
	·							
EXAMINER		DATE CONSIDERED						

<sup>\*</sup>Examiner Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.